

L Number	Hits	Search Text	DB	Time stamp
3	42	((cmp or (chemical adj mechanical adj (polishing or planarization))), and (451/\$ 156/345 216/\$).ccls.) and durometer	USPAT	2002/04/25 11:11
4	8	((cmp or (chemical adj mechanical adj (polishing or planarization))), and (451/\$ 156/345 216/\$).ccls.) and durometer and "Shore D"	USPAT	2002/04/25 11:11
5	141	("elasticity" or "elastic modulus") and ("chemical mechanical planarization" or "chemical mechanical polishing")	USPAT	2002/04/25 11:20